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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/603,012	06/24/2003	Young Sun Hwang	30205/39412	2436	
4743 75	590 07/01/2004		EXAM	EXAMINER	
	, GERSTEIN & BORUN	CHACKO DAVIS, DABORAH			
6300 SEARS T 233 S. WACKI	- ·		ART UNIT	PAPER NUMBER	
CHICAGO, IL	. 60606		1756		
			DATE MAILED: 07/01/2004	4	

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.	Applicant(s)	
·	10/603,012	HWANG ET AL.	
Office Action Summary	Examiner	Art Unit	
	Daborah Chacko-Davis	1756	
The MAILING DATE of this communication Period for Reply	appears on the cover sheet w	vith the correspondence addre	SS
A SHORTENED STATUTORY PERIOD FOR RETHE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CF after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, and If NO period for reply is specified above, the maximum statutory period for reply within the set or extended period for reply will, by so Any reply received by the Office later than three months after the nearned patent term adjustment. See 37 CFR 1.704(b).	DN. R 1.136(a). In no event, however, may a i. a reply within the statutory minimum of thi riod will apply and will expire SIX (6) MO tatute, cause the application to become A	reply be timely filed  rty (30) days will be considered timely.  NTHS from the mailing date of this comm  BANDONED (35 U.S.C. § 133).	unication.
Status			
1) Responsive to communication(s) filed on 2	4 June 2003.		
	This action is non-final.		
3) Since this application is in condition for allo		ters, prosecution as to the me	erits is
closed in accordance with the practice und			
Disposition of Claims			
4)⊠ Claim(s) <u>1-7</u> is/are pending in the application	on.		
4a) Of the above claim(s) is/are with			
5) Claim(s) is/are allowed.			
6)⊠ Claim(s) <u>1-7</u> is/are rejected.			-
7) Claim(s) is/are objected to.			
8) Claim(s) are subject to restriction ar	nd/or election requirement.		
Application Papers			
9) The specification is objected to by the Exan	niner.		
10) The drawing(s) filed on is/are: a)		by the Examiner.	
Applicant may not request that any objection to			
Replacement drawing sheet(s) including the co	<del>-</del> · · ·		1.121(d).
11) The oath or declaration is objected to by the			
Priority under 35 U.S.C. § 119			
12)⊠ Acknowledgment is made of a claim for fore	eign priority under 35 U.S.C.	§ 119(a)-(d) or (f).	
a)⊠ All b)□ Some * c)□ None of:	g., p. 10, aa., a	3 (-) (-) (-)	
1.⊠ Certified copies of the priority docum	ents have been received.		
2. Certified copies of the priority docum		Application No.	
3. Copies of the certified copies of the		•	iae
application from the International Bu	•		J
* See the attached detailed Office action for a	list of the certified copies no	t received.	
•			
Attachment(s)			
1) Notice of References Cited (PTO-892)		Summary (PTO-413)	
2) Notice of Draftsperson's Patent Drawing Review (PTO-948		(s)/Mail Date Informal Patent Application (PTO-15	2)
<ol> <li>Information Disclosure Statement(s) (PTO-1449 or PTO/SE Paper No(s)/Mail Date</li> </ol>	6) Other:		-,

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## **DETAILED ACTION**

## Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.
- 2. Claims 1-4, are rejected under 35 U.S.C. 102(e) as being anticipated by U.S. Patent Application Publication No. 2003/0008968 (Sugeta et al).

Sugeta, in [0013], [0014], and [0019], discloses a photoresist overcoating composition comprising a solvent, and a water-soluble polymer such as N,N-dimethylacrylamide (Formula I) (claims 1-2). Sugeta, in [0019], and [0021], discloses that the solvent in the composition is water (claim 3). Sugeta, in [0019], [0021], and [0023], discloses that the water-soluble polymer in the composition is in the concentration of 5 to 20% by weight (claim 4).

3. Claims 1-7, are rejected under 35 U.S.C. 102(e) as being anticipated by U.S. Patent Application Publication 2003/0219682 (Wakiya et al).

Wakiya, in [0023], and in [0043], discloses a photoresist liquid coating composition (overcoating, antireflecting) comprising a solvent, and a polymer of N,N-dimethylacrylamide (Formula I) (claims 1-2). Wakiya, in [0043], discloses that the

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solvent is water (claim 3). Wakiya, in [0039], discloses that the concentration of the polymer present in the liquid coating composition is about 20% by weight (claim 4). Wakiya, in [0076], [0077], [0078], [0080] and [0081], discloses a method of forming a pattern in the following manner; i) a chemically amplified photoresist layer is deposited on the surface of a wafer (underlying layer), ii) the liquid coating solution (overcoating composition) is applied on the photoresist layer to form an antireflective film (overcoating film) on the photoresist layer, thus completing a photoresist laminate, iii) exposing the photoresist laminate to an ArF (193nm) excimer laser, iv) post-baking the exposed photoresist laminate, and v) developing the photoresist laminate (claims 5-7).

## **Conclusion**

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Daborah Chacko-Davis whose telephone number is (571) 272-1380. The examiner can normally be reached on M-F 9:30 - 6:00. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Mark F Huff can be reached on (571) 272-1385. The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9306. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you

have questions on access to the Private PAIR system, contact the Electronic Business

Center (EBC) at 866-217-9197 (toll-free).

dcd June 26, 2004.